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J.S.S.N. 09/941,537

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Chen et al.

Group Art Unit: 1756

Serial No.: 09/941,537

Examiner: J. S. Ruggles

Filed: 08/29/2001

In Response to Office Action

Dated: 04/30/2003

For: METHOD FOR REDUCING LIGHT REFLECTANCE IN A PHOTOLITHOGRAPHIC
PROCESS

Attorney Docket No.: 67,200-477

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I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to:

Commissioner for Patents

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Date: 7/30/2003

Kathy Dixon

RESPONSE TO OFFICE ACTION

Commissioner for Patents
P.O. Box 1450
Alexandria, Va 22313-1450

Dear Sir:

In response to an Office Action mailed 04/30/2003,
please enter the following amendments and consider the following
remarks.